



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT  
Customer No. 22,852  
Attorney Docket No. 06484.0070

In re Application of:

Fu-Sheng Chen

Application No.: 09/802,924

Filed: March 12, 2001

For: ELECTROSTATIC CHUCK  
SYSTEM AND METHOD FOR  
MAINTAINING THE SAME

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Group Art Unit: 2836

Examiner: Nguyen, D

#4/A  
D. EVANS  
8.4.03

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AMENDMENT

In reply to the Office Action dated April 21, 2003, Applicant submits the following amendment and remarks. This response is due by July 21, 2003, and is timely filed.

IN THE CLAIMS:

Please cancel claims 2 and 10-16, without prejudice or disclaimer, amend claim 1, and add new claim 19 as follows:

1. (Amended) A chuck system for supporting a semiconductor wafer, comprising:  
a chuck platform for supporting the semiconductor wafer; and  
a lift structure movably coupled with the chuck platform to receive the semiconductor wafer, including  
a lift base, and

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